

Virtual Equipment A Test Bench for Virtual Metrology Algorithms

(WP 2 - Task 2.5)

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Outline

- Virtual metrology (VM)
 - Objectives and benefits
 - Challenges
- Virtual Equipment (VE) concept
 - Purpose of the Virtual Equipment
 - From the first to the second approach
- Current implementation of the Virtual Equipment
 - Statistical Simulation
 - Physical Simulation
 - Short demonstration
- Conclusion







VM objectives

• Predict post process physical and electrical quality parameters of wafers and/or devices from information collected from the manufacturing tools including support from other available information sources in the fab

VM benefits

- Support or replacement of stand-alone and in-line metrology operations
- Support of FDC, run-to-run control, and PdM
- Improved understanding of unit processes







VM challenges and questions

- VM algorithms tend to be at the same time generic statistical modelling as well as very specific in the area they excel
 - Test needed for optimal matching and accuracy of a specific VM technique in an existing fabrication line
 - Test of VM algorithms on real equipment can be expensive and usually does not cover uncommon equipment states

• Solution: Virtual Equipment

- Comparison of different VM algorithms
- Evaluation of the sensitivity of VM algorithms to errors





Concept "Virtual Equipment"

- Definition and setup of a Virtual Equipment (VE) as a benchmark tool
 - ► Utilization of history fab data
 - Simulation of relevant equipment and process behaviour
 - Application of typical faults, process drifts, mix and match scenarios and noise effects
- Convenient operation through a graphical user interface
- Usage of Matlab/Simulink





















Concept "Virtual Equipment"







Concept "Virtual Equipment"









- Fab data input from Excel or CSV table
- Statistical changes to input data:
 - ▶ Noise, Drift, ...
 - Bayesian Network
 - Fab Data as Learning Data
 - Soft discretization
 - Prediction of signal depending on changed other signals
- Physical simulation
 - Uses Comsol (very flexible, extendable multiphysics simulator for flow, plasma, structure, …)
 - Statistically changed data as boundary conditions
 - Computation of sensor signals
 - Prediction of process result (quality parameters)
 - Interpolation from stored results possible







Current implementation

- Virtual Metrology Algorithms get the generated signals as input data
 - Same input data for all VMs to compare
 - Prediction of the same quality parameter
- Comparison of predicted values
 - between VM algorithms
 - to Metrology data from either fab data or physical simulation
- Computation of Measurement Capability of VM algorithms







Short demonstration "Virtual Equipment"

- Demonstration of a simple exemplary scenario on the Virtual Equipment
- Fictional input fab data set used (not from a real equipment)
- Simple exemplary VM algorithms
 - Linear Combination with fixed coefficients
 - ► Linear Regression







- Achievements:
 - Capability to compare multiple VM models
 - Generation of test data sets for common and uncommon situations
 - Integration of statistical and physical simulation
 - Evaluation of measurement capability and sensitivity of VM algorithms
- Plans:
 - Nearly ready: Automated studies of VM behavior given a sequence of fault parameters (e.g. gage capability over noise strength)
 - Autumn 2011: Test of VM models with the Virtual Equipment
 - ► End of 2011: More physical simulation models added to VE
 - End of 2011: Integration with IMPROVE Framework







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